



PROCESS FOR CALIBRATING INTERFEROMETER INTERPIXEL DEFECTS

Innovative process for calibrating a detector matrix to correct gain variations between pixels in an interferometer.

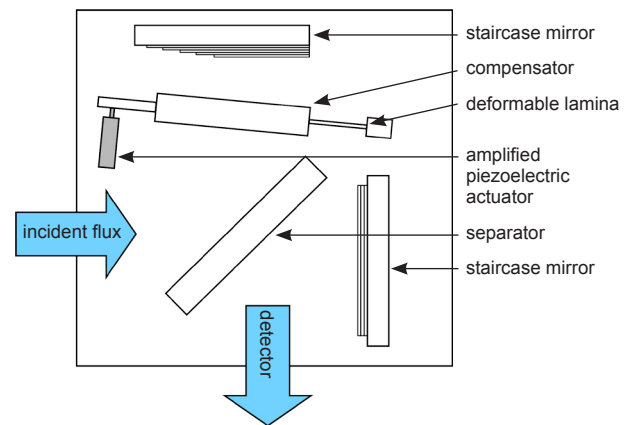
Technological benefits

Reliable mechanism

Short travel compatible with a piezoelectric system
No need for external mechanisms such as a baffle

High-performance calibration

Pixel-by-pixel calibration
Precision of around 0.1 %
Calibration possible throughout instrument lifetime
All instrument systems and subsystems taken into account
Simplified gain calculation



Block diagram

Invention overview

Device generating a known signal variation for each pixel so as to match the calibration of the multi-pixel sensor.

The operating principle lies in varying the path difference along one of the interferometer's two arms very slightly using a reliable device.

Commercial benefits

Robust

Very reliable
Limited maintenance

Compact

Compact mechanism

Potential applications

Improving interferometers

Remote sensing from space, detection of gas in automated units

Patented invention, available under licence